

ABSTRACT

The object is to reduce the total processing time by transferring the substrate at the first delivery stage to the process block where processing can be carried out earliest.

5 The substrate processing apparatus includes first transfer means (22) for delivering a wafer (W) with respect to a substrate carrier (C), and second transfer means (23) for delivering a wafer (W) between a plurality of process blocks (B3-B5) and the first transfer means (22) via a first delivery stage (24), to transfer the wafer (W) with respect to the process blocks (B3-B5). In this apparatus, the process block where there is no
10 wafer (W) or where processing of the last wafer (W) within the relevant process block will be completed earliest is determined based on processing information of the wafers (W) from the process blocks (B3-B5), and the wafer (W) of the first delivery stage (24) is transferred by the second transfer means (23) to the relevant process block. This ensures smooth transfer of the wafer (W) to the process block.